

# Integrated Modeling Tool for Electron-Beam Based Ion-Sources\*

Phase II: 8/8/12 - 8/7/15

J.S. Kim (P.I.), L.Zhao, J.A. Spencer and E.G. Evstatiev

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FAR-TECH, Inc., 10350 Science Center Drive, Suite 150, San Diego, CA 92121 Tel: (858) 455-6655, Fax (858) 450-9741 www.far-tech.com

#### FAR-TECH, Inc. Management and Facility

- Located in San Diego, CA
- Founded in 1994, formerly known as Fusion and Accelerator Research (FAR), to pursue fusion and accelerator related research, technology and development.
- Core staff of over 10 PhDs Physics/Engineering
- Facility:
  - Linux cluster (88 processors) with 96GB of memory via Infiniband connection; 15 TB redundant storage
  - RF, UHV, laboratory and assembly





Linac Systems: Structure RF source Integration Beam Instrumentation Solid State Amplifier





Modeling tools for: Plasma Beam Ion source

Fluid & PIC Simulations

**Visualization** 

**Graphical User Interface** 





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New technique
New devices
New diagnostics
Fundamental
knowledge discovery

## **Project Overview**

Integrated Modeling Tool for Electron-Beam based Ion-Sources (EBIS)

**Project period:** 8/8/12 – 8/7/15 (1 year no-cost extension)

Goal: Develop a numerical tool to help the operation and design of EBIS.

NP Relevance: EBIS is a leading technology for HCIs which are needed for NP studies. Our modeling tool helps to optimize current device operations and will assist the design of future devices. Extremely important for RIBs as experimental trial-and-errors must be minimized.

Schedule: Primary objective is essentially met. Remaining work: more validation, speedup and GUI



# **Brief description of EBIS**

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# **Brief description of EBIS**









# **EBIS-PIC** modeling

Electron and ion space charge modeled self-consistently.

Important atomic processes are included via Monte Carlo collision algorithm. They include:

- Ionization
- Charge exchange and recombination
- Radiative recombination
- Coulomb collisions with electrons,

primary ions and neutral gas ions



# **Example Case: BNL Test EBIS Device**



Parameters	Value
Drift tube length	1.07 m
Drift tube radius	1.5 cm
Drift tube voltage	6-13 kV
Magnetic field	5 T
Electron beam current	<b>1.0</b> -1.5 A
Electron beam radius	0.75 mm
Pressure	5e-10 Torr
Ion Species	Cs



### **Electron Beam Simulation by PBGUNS**





#### Cs Charge State Distribution After ~5.3 ms Trapping



# **CPU consideration and Practical Computation**



Use lower dimensional calculation when approximation is justifiable. Simulate EBIS-PIC 2D for a few msec, until ions are populated approximately uniformly in z, then reduce to 1D (r). Simulate charge breeding until necessary, then back to 2D if possible (?) to obtain full emittance.

Use 0D as baseline.



# 1D simulation by EBIS-PIC 1D (r)

Snapshots of CSD,  $n_i$ ,  $\phi$ ,  $\rho_i$ at t = 0, 10 & 20 ms

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#### **0-D calculation by Chaser**



#### Chaser v1.0

*Chaser*, the *CHArge State EstimatoR*, simulates the time Evolution of charge states of ions in charge breeders.

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www.far-tech.com/chaser



Primary objective is met. Remaining work: more validation, speedup and GUI

Community (EBIS/EBIT) support and commercialization

FAR-TECH's EBIS modeling tool consists of:

**PBGUNS** (particle beam gun simulation code) : Most 2D beams can be simulated. Input parameter GUI with geometry viewing

**Chaser:** Charge State Estimator (0D) – good basis as a start

EBIS-PIC: 1D – long time charge breeding ( > tens of ms) 2D – short time charge breeding ( < tens of ms)





Fusion and Accelerator Research and Technology, San Diego CA

Beam Source Modeling Plasma Technology: Modeling and Diagnostics

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www.far-tech.com

support@far-tech.com

